



systems, collision avoidance radars, next-generation transport communications, and wireless-local-area-networks (WLAN). Among the improvements of the researchers' devices was reducing gate lengths to 25nm, boosting frequency performance.

The metal-organic chemical vapor deposition (MOCVD) epitaxial heterostructure was grown on 3-inch semi-insulating indium phosphide (InP) substrate. The layer sequence was 200nm  $\text{In}_{0.52}\text{Al}_{0.48}\text{As}$  buffer, 9nm InGaAs quantum well channel, 9nm  $\text{In}_{0.52}\text{Al}_{0.48}\text{As}$  barrier/spacer, 3nm InP etch stop, and 30nm heavily doped  $\text{In}_{0.52}\text{Al}_{0.48}\text{As}/\text{In}_{0.53}\text{Ga}_{0.47}\text{As}$  multi-layer cap.

The barrier/spacer layer was delta-doped with silicon. The cap was designed to reduce source/drain contact resistance. The channel layer had three components — 3nm  $\text{In}_{0.53}\text{Ga}_{0.47}\text{As}$ , 5nm  $\text{In}_{0.8}\text{Ga}_{0.2}\text{As}$ , and 1nm  $\text{In}_{0.53}\text{Ga}_{0.47}\text{As}$ . Hall measurements gave  $\sim 3 \times 10^{12}/\text{cm}^2$  two-dimensional electron gas density (2DEG) and mobility of  $13,500\text{cm}^2/\text{V}\cdot\text{s}$  at 300K.

The epitaxial material was fabricated into HEMTs with recessed gates. The gate-to-channel distance was 5nm; the source-drain spacing was  $0.8\mu\text{m}$ . The Ohmic source/drain contacts consisted of titanium/molybdenum/titanium/platinum/gold. The platinum/titanium/platinum/gold T-gates were formed with the help of silicon dioxide. Gate lengths as short as 25nm were achieved.

The 25nm-gate device had a DC on-resistance of  $279\Omega\cdot\mu\text{m}$ , while the contact resistance was  $40\Omega\cdot\mu\text{m}$ . The peak transconductance was  $2.8\text{mS}/\mu\text{m}$  with the drain bias ( $V_{\text{DS}}$ ) at 0.8V. The subthreshold swing was 100mV/decade; the drain-induced barrier lowering (DIBL) was 120mV/V.

Measurements in the range 1–50GHz gave a cut-off frequency ( $f_{\text{T}}$ ) and a maximum oscillation frequency ( $f_{\text{max}}$ ) of 703GHz and 820GHz, respectively, for 25nm-gate HEMTs with  $2 \times 20\mu\text{m}$  width (Figure 1). The drain and gate ( $V_{\text{GS}}$ ) biases were 0.5V and 0.15V, respectively. These offset values were chosen to put the HEMT near the peak transconductance state.

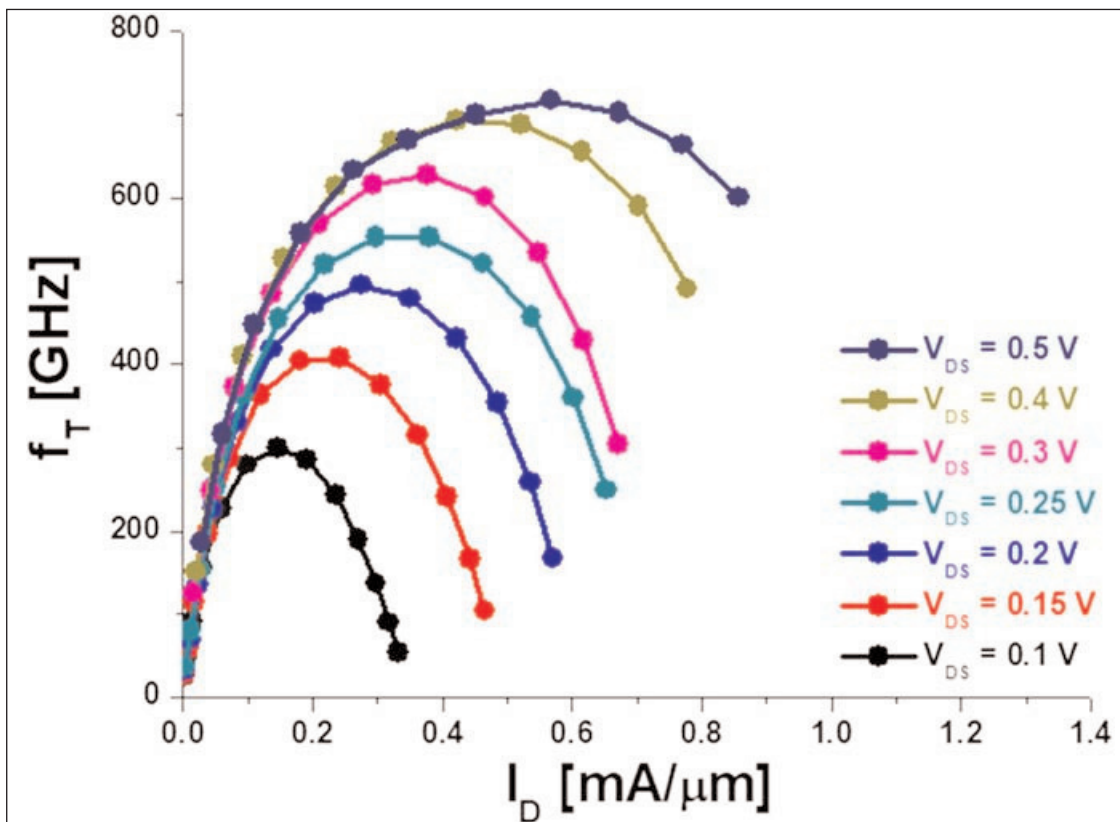


Figure 2. Measured  $f_{\text{T}}$  against drain current ( $I_{\text{D}}$ ) with various  $V_{\text{DS}}$ .

There were problems in estimating  $f_{\text{max}}$  due to “sharp peaky behavior” of Mason’s unilateral power gain ( $U_{\text{g}}$ ) with respect to frequency. The 820GHz  $f_{\text{max}}$  value was derived through a small-signal model from which a well-behaved gain parameter was extracted.

The researchers comment: “It is true that there exists inconsistency between the measured and the modeled  $U_{\text{g}}$ , especially in the low-frequency regime. This is due to the fact that our small-signal model did not take the effect of impact ionizations in the InGaAs QW channel into account. Nevertheless, this kind of the small-signal model has provided a reasonable estimate on  $f_{\text{max}}$ , since the effect of the impact-ionizations diminishes as the measured frequency goes over 10GHz.”

The small-signal model was also used to extrapolate the maximum stable gain (MSG) and maximum available gain (MAG) values. The  $f_{\text{max}}$  of 820GHz was also consistent with the MSG/MAG behavior. The  $f_{\text{T}}$  value was derived from extrapolation of the short-circuit current-gain ( $|h_{21}|^2$ ).

The team point out that the  $f_{\text{T}}$  and  $f_{\text{max}}$  values above 700GHz were obtained using the same bias conditions, unlike in other reports on high-speed transistors.

The researchers also studied the  $f_{\text{T}}$  variation with drain current and bias (Figure 2). The team points out that at drain currents typical for low-noise amplifiers ( $0.1\text{A}/\mu\text{m}$ ) the  $f_{\text{T}}$  value was still more than 400GHz. ■

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